



7/Response
Electron
5-1-03

PATENT
04600/USA/IMPLANT/ORION/LE
BSKB DOCK. NO. 1028-0171P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: LEDOUX et al. Conf.: 7224
Appl. No.: 09/822,864 Group: 2881
Filed: April 2, 2001 Examiner: Nguyen, K.T.
For: METHOD AND SYSTEM FOR CONTROLLING BEAM
SCANNING IN AN ION IMPLANTATION DEVICE

RESPONSE TO RESTRICTION REQUIREMENT

Assistant Commissioner for Patents
Washington, DC 20231

April 28, 2003

Sir:

In reply to the Restriction Requirement dated February 26, 2003, the period for response having been extended one (1) month to expire on April 26, 2003, the following remarks are respectfully submitted in connection with the above-identified application.

RECEIVED
MAY - 1 2003
TECHNOLOGY CENTER 2800